

Doping the Undopable: Hybrid Molecular Beam Epitaxy Growth, n-Type Doping, and Field-Effect Transistor Using CaSnO_3

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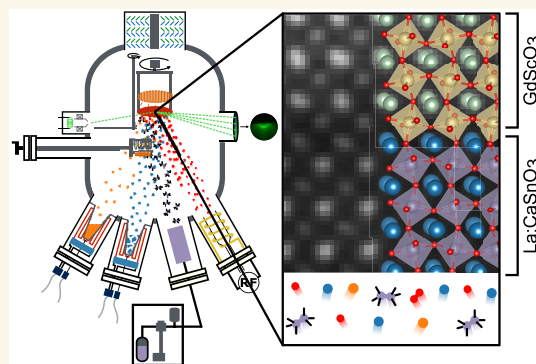
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ABSTRACT: The alkaline earth stannates are touted for their wide band gaps and the highest room-temperature electron mobilities among all of the perovskite oxides. CaSnO_3 has the highest measured band gap in this family and is thus a particularly promising ultrawide band gap semiconductor. However, discouraging results from previous theoretical studies and failed doping attempts had described this material as “undopable”. Here we redeem CaSnO_3 using hybrid molecular beam epitaxy, which provides an adsorption-controlled growth for the phase-pure, epitaxial, and stoichiometric CaSnO_3 films. By introducing lanthanum (La) as an n-type dopant, we demonstrate the robust and predictable doping of CaSnO_3 with free electron concentrations, n_{3D} , from $3.3 \times 10^{19} \text{ cm}^{-3}$ to $1.6 \times 10^{20} \text{ cm}^{-3}$. The films exhibit a maximum room-temperature mobility of $42 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ at $n_{3D} = 3.3 \times 10^{19} \text{ cm}^{-3}$. Despite having a comparable radius as the host ion, La expands the lattice parameter. Using density functional calculations, this effect is attributed to the energy gain by lowering the conduction band upon volume expansion. Finally, we exploit robust doping by fabricating CaSnO_3 -based field-effect transistors. The transistors show promise for CaSnO_3 's high-voltage capabilities by exhibiting low off-state leakage below $2 \times 10^{-5} \text{ mA/mm}$ at a drain–source voltage of 100 V and on–off ratios exceeding 10^6 . This work serves as a starting point for future studies on the semiconducting properties of CaSnO_3 and many devices that could benefit from CaSnO_3 's exceptionally wide band gap.

KEYWORDS: ultrawide band gap (UWBG) semiconductors, hybrid molecular beam epitaxy (hMBE), calcium stannate, chemical doping, density functional calculations, metal–semiconductor field-effect transistor (MESFET), high-voltage electronics



INTRODUCTION

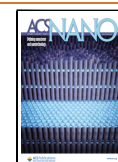
Alkaline earth stannates have been among the most exciting materials for research in the past decade, due to their wide band gaps and their high room-temperature electron mobilities.¹ In particular, BaSnO_3 has a band gap of 3.1 eV^{2,3} and room-temperature electron mobility as high as $320 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ in bulk single crystals, the highest among all perovskite oxides.¹ Thin-film BaSnO_3 , however, has achieved a mobility of only $183 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$.⁴ Researchers attribute this discrepancy to the high density of threading dislocations resulting from the large lattice mismatch with commercially available substrates.^{5,6} Replacing Ba with the smaller Sr to counter the lattice mismatch produces SrSnO_3 with a wider band gap of 4.1 eV^{2,3} and a room-temperature mobility as high as $72 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ in thin films.⁷ These make SrSnO_3 an attractive ultrawide band gap (UWBG) semiconductor for high-performance radio

frequency (RF) devices.^{8,9} Even though SrSnO_3 can be grown coherently on GdScO_3 (110) substrates due to its smaller lattice parameter,^{10–12} above a critical thickness of 12–26 nm, a structural phase transition and subsequent strain relaxation lead to substantial structural degradation.⁷ Additionally, SrSnO_3 is also sensitive to temperature,¹³ composition,¹⁴ and biaxial strain,¹¹ which complicates its implementation in devices.

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CaSnO₃ inherently overcomes the lack of lattice matched substrates (in the case of BaSnO₃) and structural sensitivity (in the case of SrSnO₃). It is remarkably comfortable in its orthorhombic structure (shown in Figure 1a), insensitive to

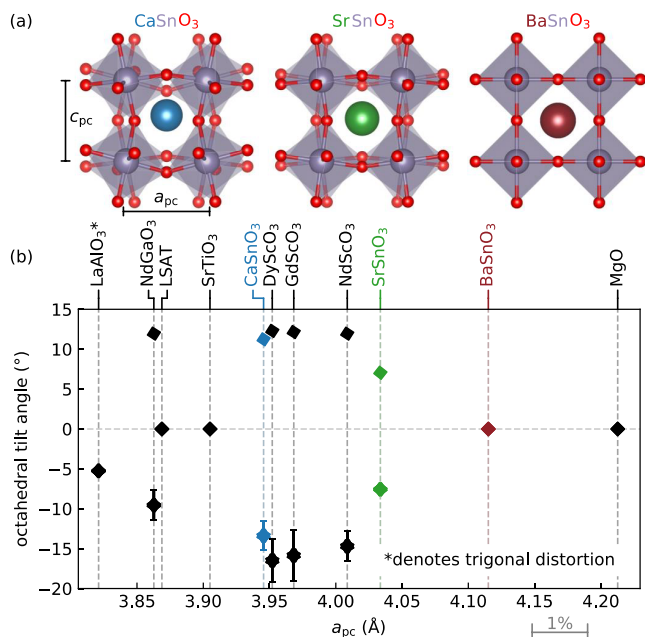


Figure 1. (a) Crystal structures of the alkaline earth stannates (CaSnO₃, SrSnO₃, and BaSnO₃) from Mountstevens *et al.*¹⁴ (b) Pseudocubic lattice parameters (a_{pc}) and octahedral tilt angles of the stannates and commercially available single-crystal substrates. Tilt angles were calculated using the B–B–B–O dihedral angles, shown with positive angles representing in-phase tilts and negative angles representing antiphase tilts. The error bars represent ambiguity in the angles due to octahedral distortions.

extreme temperatures,¹⁵ pressures,¹⁶ and compositional changes.¹⁴ Only under the exceptionally extreme conditions of 2000 K and 50 GPa does CaSnO₃ exhibit a phase transition out of its orthorhombic symmetry into an edge-sharing postperovskite structure.¹⁷ Replacing Ba or Sr with Ca further decreases the pseudocubic lattice parameter of CaSnO₃ to $a_{pc} = 3.95$ Å,¹⁴ putting its lattice parameter closer to several commercially available perovskite oxide substrates with the same space group and similar octahedral tilt angles (Figure 1b).^{14,18} These qualities suggest that epitaxial CaSnO₃ might achieve structural quality akin to that typically achieved in homoepitaxial perovskites. The small Ca²⁺ A-site cation also achieves the largest octahedral tilt angles of the three stannates, as shown in Figure 1b. This decreases the conduction band dispersion, enlarging the band gap to 4.4 eV.^{2,3} The Baliga figure of merit (BFOM), which quantifies a material's suitability for power electronics, is proportional to the band gap cubed.¹⁹ Therefore, this small increase in the band gap potentially gives CaSnO₃ a substantial advantage over SrSnO₃.

Despite all of these promising fundamental properties, CaSnO₃'s semiconducting properties have been, until now, unrealized. Wei *et al.* grew 3% La-doped CaSnO₃ by pulsed laser deposition (PLD) in an attempt to characterize its semiconducting properties, but the films did not exhibit measurable conductivity despite SrSnO₃ and BaSnO₃ achieving robust conductivity under similar growth conditions.²⁰ Perhaps this result was unsurprising given that Weston *et al.* had already

warned that "doping [CaSnO₃] looks particularly challenging"²¹ from their theoretical studies. Shaili *et al.* have arguably achieved Nd doping in polycrystalline CaSnO₃ films, but the room-temperature mobility remained <4 cm² V⁻¹ s⁻¹.²²

Here, by growing CaSnO₃ on GdScO₃ (110) substrates within an adsorption-controlled growth window using hybrid molecular beam epitaxy, we show that CaSnO₃ not only can be doped but can achieve *robust and predictable* doping that spans a 5-fold range of carrier concentrations. It is noted that despite having ideally lattice-matched DyScO₃ (110) substrates, GdScO₃ substrates were chosen due to their low lattice mismatch and tilt mismatch (Figure 1b) because it allows for the unambiguous determination of the out-of-plane lattice parameter of films owing to distinct peaks from the film and the substrate.

Good room-temperature mobilities can also be achieved up to 42 cm² V⁻¹ s⁻¹. In addition, we demonstrate the potential of this UWBG semiconductor by fabricating field-effect transistors (FETs) that use CaSnO₃ as the channel material. The transistors exhibit an on–off ratio exceeding 10⁶ and off-state leakage below 10⁻⁶ mA/mm at a drain–source voltage (V_{DS}) of 1 V, attesting to the high degree of doping control. The transistors also exhibit outstanding high-voltage capabilities, with off-state leakage of $<2 \times 10^{-5}$ mA/mm at a source–drain voltage of 100 V, demonstrating CaSnO₃'s promise for high-voltage devices. We conclude by discussing why our doping attempts have succeeded, whereas previous attempts have failed.

RESULTS

We begin our study of CaSnO₃ by growing 65 nm La:CaSnO₃ on a GdScO₃ (110) substrate. Here, we fixed the Ca flux and varied hexamethylditin (HMDT) to achieve different HMDT/Ca beam equivalent pressure (BEP) ratios ranging from 877 to 1158 to explore cation stoichiometry. La flux was also kept unchanged by fixing La-cell temperature. The reflection high energy electron diffraction (RHEED) patterns in Figure S1 exhibit tall streaks, which indicate a smooth surface, bright half-order streaks, which correspond to the unit-cell doubling caused by CaSnO₃'s large octahedral tilting, and Kikuchi lines, which indicate high crystalline quality, all three of which show no discernible dependence on BEP ratio. The representative atomic force micrograph in Figure S2 has an RMS surface roughness of 227 pm, consistent with the streaky RHEED images. The high-resolution X-ray diffraction (HRXRD) coupled scans of these samples show clear Laue oscillations, which demonstrate uniform films with a high structural quality (Figure 2a). The film rocking curves shown in Figure S3 exhibit full widths at halfmaximum (FWHM) of 0.024–0.038°, with no clear dependence on BEP ratio. These are broader than the substrate rocking curves (FWHM \approx 0.006°), but are at least 7-fold narrower than the narrowest film rocking curve (FWHM = 0.27°) in the existing CaSnO₃ literature.²³

From the HRXRD coupled scans, we calculated the out-of-plane lattice parameters c_{pc} of the La:CaSnO₃ films grown under different BEP ratios, as shown in Figure 2b. We found that c_{pc} of all the films showed no obvious dependence on the BEP ratio, a behavior dissimilar to BaSnO₃, where a Sn deficiency manifests as an expanded lattice parameter.²⁴ More surprisingly, the film lattice parameters were very close to the bulk lattice parameter (within 0.04%), despite being tensile-strained (0.38%) to the GdScO₃ substrate indicated by the reciprocal space map of the (103)_{pc} region in the inset of

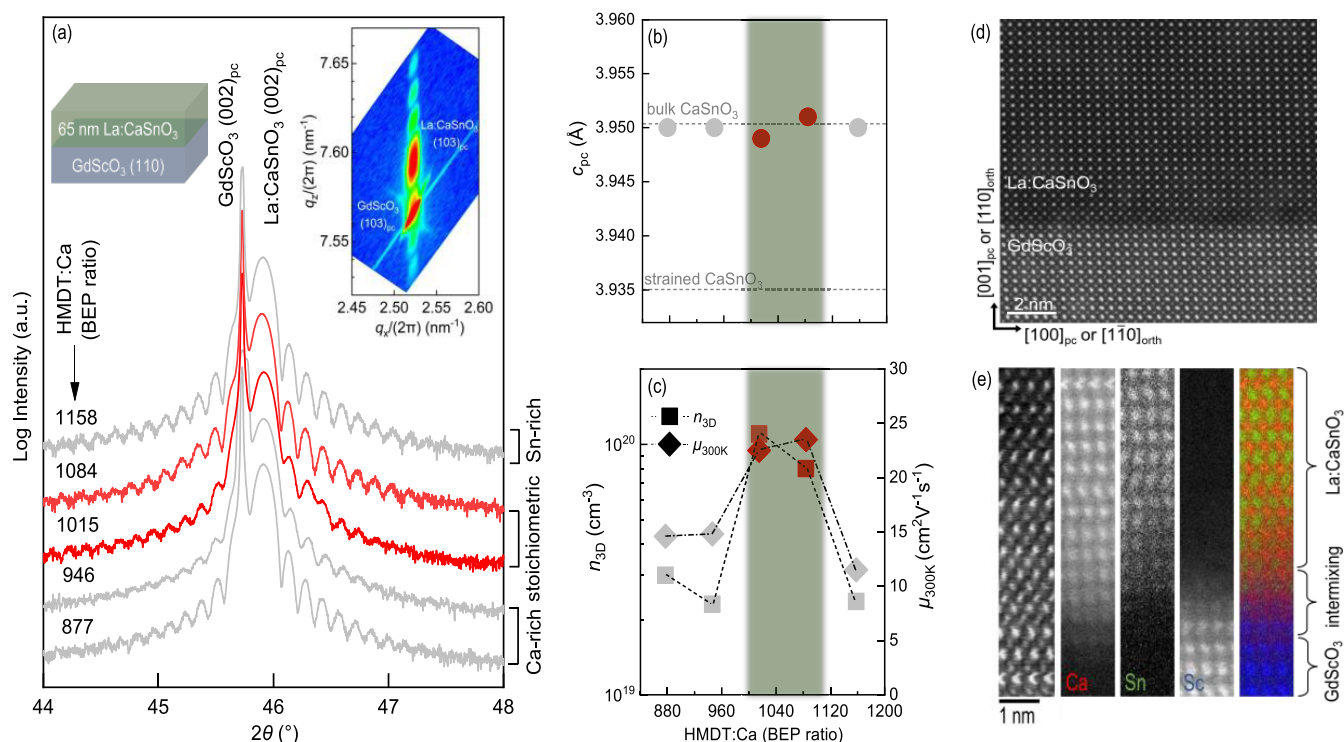


Figure 2. (a) High-resolution X-ray diffraction 2θ - ω coupled scans of 65 nm La:CaSnO₃/GdScO₃ (110) grown with different HMDT:Ca BEP ratios. The left-side inset shows a schematic of the sample structure. The right-side inset shows an asymmetric reciprocal space map around the (103)_{pc} reflection for a BEP ratio = 1015. (b) Out-of-plane pseudocubic lattice parameters, c_{pc} , for different BEP ratios. Dashed lines indicate the out-of-plane pseudocubic lattice parameter corresponding to the bulk CaSnO₃ and a fully strained CaSnO₃ film on a GdScO₃ (110) substrate. (c) Room-temperature carrier concentrations n_{3D} and mobilities μ_{300K} plotted against the BEP ratio. (d) Cross-sectional HAADF-STEM of the La:CaSnO₃/GdScO₃ interface for BEP ratio = 1015, imaged along the [001]_{orth} zone axis. (e) STEM electron energy loss spectroscopy (EELS) elemental maps showing intermixing between the GdScO₃ substrate and La:CaSnO₃ film.

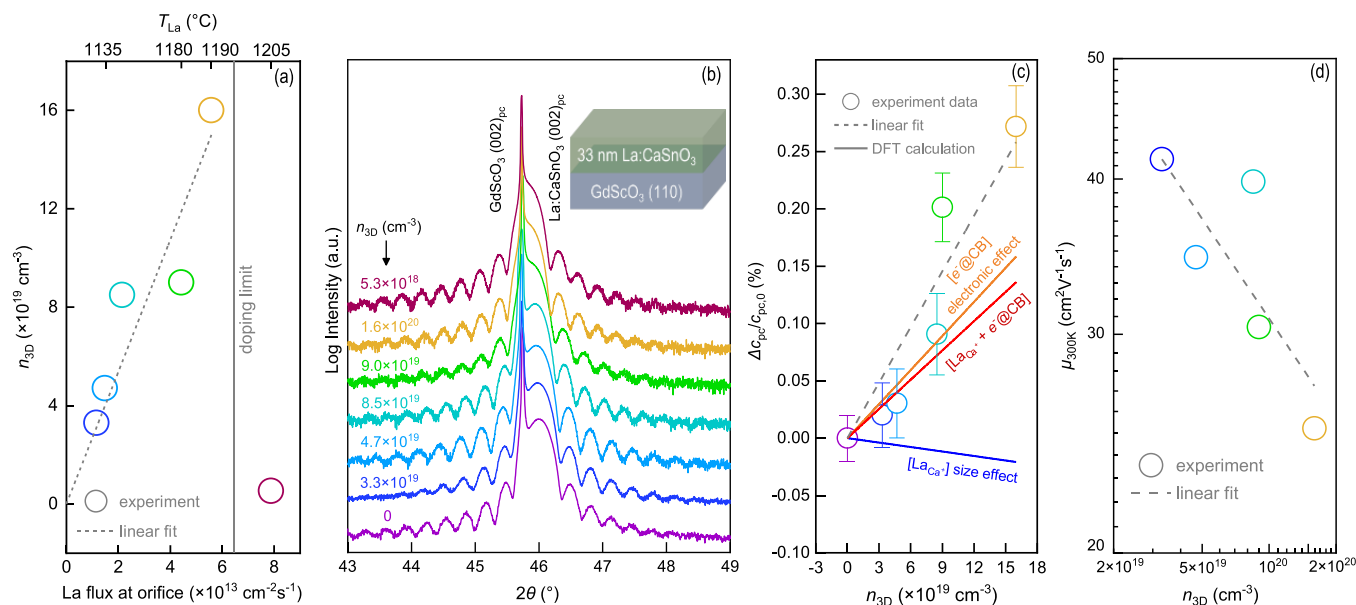


Figure 3. (a) Room-temperature carrier concentration n_{3D} as a function of the La flux at the crucible orifice, controlled by the effusion cell temperature. A proportional fit to the data is shown with a dashed line. (b) High-resolution X-ray diffraction 2θ - ω coupled scans of La:CaSnO₃/GdScO₃(110) with various carrier concentrations n_{3D} . The inset shows a schematic of the sample structure. (c) Expansion of the out-of-plane lattice parameter Δc_{pc} with respect to $c_{pc,0}$ (undoped lattice parameter) as a function of the carrier concentration n_{3D} . The experimental data points are shown as circles with a proportional fit shown with a dashed line. DFT predictions are shown as solid lines including the La size effect, the electronic effect, and the two effects together. (d) Room-temperature electron mobility μ_{300K} as a function of the carrier concentration n_{3D} . A guide to the eye is shown as a dashed line.

Figure 2a. We later explain that the expanded lattice parameters is because of electronic carrier-induced lattice expansion.

To probe the cation stoichiometry of the films more sensitively, we performed room-temperature Hall measurements of the films and extracted the carrier concentrations (n_{3D}) and mobilities (μ_{300K}) as a function of the HMDT/Ca BEP ratio, shown in **Figure 2c**. At extreme BEP ratios, the mobilities are relatively low ($12\text{--}15\text{ cm}^2\text{ V}^{-1}\text{ s}^{-1}$), whereas at intermediate BEP ratios, the mobilities are much higher ($22\text{--}24\text{ cm}^2\text{ V}^{-1}\text{ s}^{-1}$), a trend similar to BaSnO_3 ²⁴ and SrSnO_3 .¹⁰ The carrier concentration also shows a similar trend. These intermediate BEP ratios between 1015 and 1084 constitute a growth window represented by the green shaded region in **Figure 2c**, in which the 1:1 Sn:Ca cation stoichiometry is self-regulated and thus impervious to flux instabilities. Here, the higher HMDT/Ca BEP ratios refer to Sn-rich growth conditions, whereas the lower HMDT/Ca BEP ratios indicate Ca-rich conditions. Whether the decrease in n_{3D} and μ_{300K} (outside the growth window) is related to Ca- or Sn-vacancies or related defect complexes remains unclear and should be investigated using more sensitive techniques such as positron annihilation.

Figure 2d shows a high-angle annular dark-field scanning transmission electron microscopy (HAADF-STEM) image of the $\text{La:CaSnO}_3/\text{GdScO}_3(110)$ interface down the $[001]_{\text{orth}}$ zone axis for the sample growth with a BEP ratio = 1015. The image shows a clearly epitaxial relationship and a coherent interface consistent with the RSM map. The Ca and Gd columns are both elliptical, reflecting the A-site alternating displacements, which are visible only in the $[001]_{\text{orth}}$ zone axis. This indicates a $(110)_{\text{orth}}\parallel(110)_{\text{orth}}$ and $[001]_{\text{orth}}\parallel[001]_{\text{orth}}$ epitaxial relationship. Consistent with a fully strained film, these results combined with a low-resolution STEM HAADF image (**Figure S4**) reveal no measurable dislocations. The reader may wonder, why does the polar discontinuity between locally polar GdScO_3 and nonpolar CaSnO_3 produce a two-dimensional carrier gas? The STEM electron energy loss spectroscopy (EELS) maps in **Figure 2e** and the additional analysis in **Figure S4** show that there is significant intermixing between the substrate and film cations. This likely results from using untreated substrates that do not exhibit an atomically abrupt surface or preferential surface termination. This intermixing prevents the abrupt interface required to produce the polar discontinuity, which leads to the formation of a two-dimensional carrier gas. Future studies might explore the possibility of growing CaSnO_3 on rare earth scandate substrates treated to achieve an atomically abrupt surface with defined A-site or B-site termination.^{25,26}

Whereas, in the previous section, we used various BEP ratios and a fixed La effusion cell temperature of $T_{\text{La}} = 1190\text{ }^\circ\text{C}$ to optimize the cation stoichiometry, we now show results from films grown with a fixed BEP ratio of 1015 (inside the growth window) and T_{La} varying from 1120 to 1205 $^\circ\text{C}$ to study doping. **Figure 3a** shows the n_{3D} as a function of the La flux at the crucible orifice, calculated from the kinetic theory of gases as done previously for Nd:SrSnO_3 .²⁷ The film grown at $T_{\text{La}} = 1120\text{ }^\circ\text{C}$ did not show measurable conductivity. There are no reliable measurements or calculations of CaSnO_3 's effective mass, m^* , or dielectric constant, ϵ_r , so the Mott critical carrier concentration n_c cannot be calculated with great accuracy.²⁸ However, using m^* and ϵ_r of BaSnO_3 ($m^* = 0.2\text{--}0.4m_e$ and $\epsilon_r = 20$)^{29,30} and SrSnO_3 ($m^* = 0.3\text{--}0.4m_e$ and $\epsilon_r = 17$),¹¹

reasonable inclusive ranges of $0.3 < m^*/m_e < 0.5$ and $10 < \epsilon_r < 20$ yield a range of $4.0 \times 10^{17}\text{ cm}^{-3} < n_c < 1.5 \times 10^{19}\text{ cm}^{-3}$, which is much lower than the minimum n_{3D} in **Figure 3a**. Therefore, the lack of conductivity at $T_{\text{La}} = 1120\text{ }^\circ\text{C}$ must be explained by another mechanism, such as compensation or localization of the free carriers. The plot of the conductive samples in **Figure 3a** shows two regions. In the region to the left of $T_{\text{La}} = 1195\text{ }^\circ\text{C}$, the data can be modeled by a straight line with a y -intercept of zero. This is strong evidence of 100% doping activation and one-to-one correlation between dopant concentration and carrier density. It is noted that La concentration in our films varies between 0.19 and 1.0 at. %. Since the nature of intrinsic defects is unclear, we do not express La concentration using a chemical formula such as $\text{Ca}_{1-x}\text{La}_x\text{SnO}_3$. In the region to the right of $T_{\text{La}} = 1195\text{ }^\circ\text{C}$, the film shows the lowest n_{3D} of all the films, despite being grown at the highest T_{La} . This suggests a doping limit of $\sim 1.6 \times 10^{20}\text{ cm}^{-3}$, above which La dopants either aggregate to form a secondary phase such as pyrochlore-type $\text{La}_2\text{Sn}_2\text{O}_7$ ³¹ or self-compensate by occupying the Sn site.²¹ Regardless of the mechanism behind the doping limit, the carrier concentrations from $3.3 \times 10^{19}\text{ cm}^{-3}$ to $1.6 \times 10^{20}\text{ cm}^{-3}$ in the left-side region of **Figure 3a** provide a 5-fold range of controlled carrier concentrations that can be used in electronic devices.

Before discussing our CaSnO_3 devices, however, we first discuss the structural changes resulting from the free electrons and their mobilities with doping. The rocking curves for these films, shown in **Figure S5**, exhibit FWHM values that vary from 0.026° to 0.041° , suggesting high structural quality that is not degraded by doping. **Figure 3b** shows the HRXRD coupled scans of these films. The patterns are mostly identical, the only discernible trend being that the film peaks coalesce with those of the substrate when $T_{\text{La}} \geq 1180\text{ }^\circ\text{C}$, indicating that doping expands the lattice parameter. To extract the lattice parameters of these thinner films, we simulate their diffraction patterns with GenX 3;³² the fits are shown in **Figure S6a** and the extracted lattice parameters are plotted versus n_{3D} in **Figure S6b**. This expansion with doping explains why the films described in **Figure 2b** exhibit bulklike out-of-plane lattice parameters despite being tensile-strained to GdScO_3 . However, this lattice expansion is somewhat surprising given the comparable radius of La^{3+} compared to that of Ca^{2+} in the 12-fold coordination environment, as shown in **Figure S7**, which suggests that another mechanism, perhaps electronic, is at play.

To disentangle the ionic size and electronic effects on the lattice parameters, we turn to density functional theory (DFT). We find that adding one electron to the conduction band of the epitaxially strained CaSnO_3 leads to an increase in the out-of-plane c lattice parameter (pure electronic effect), whereas adding La without the extra electron leads to a decrease in the c lattice parameter (size effect), as shown in **Figure 3c**. The combined electronic and size effects, simulated by adding both La and its extra electron, result in a net expansion of the lattice, also shown in **Figure 3c**, in agreement with the trend we observed in our experiments. The effect of lattice expansion upon doping is attributed to the lowering of the conduction band minimum (CBM) as the volume increases. This arises from the negative value of the conduction band absolute deformation potential;^{33,34} that is, as the volume increases, the CBM is lowered in an absolute energy scale due to its antibonding nature. If the conduction band edge states are occupied through doping, then the whole crystal lowers its

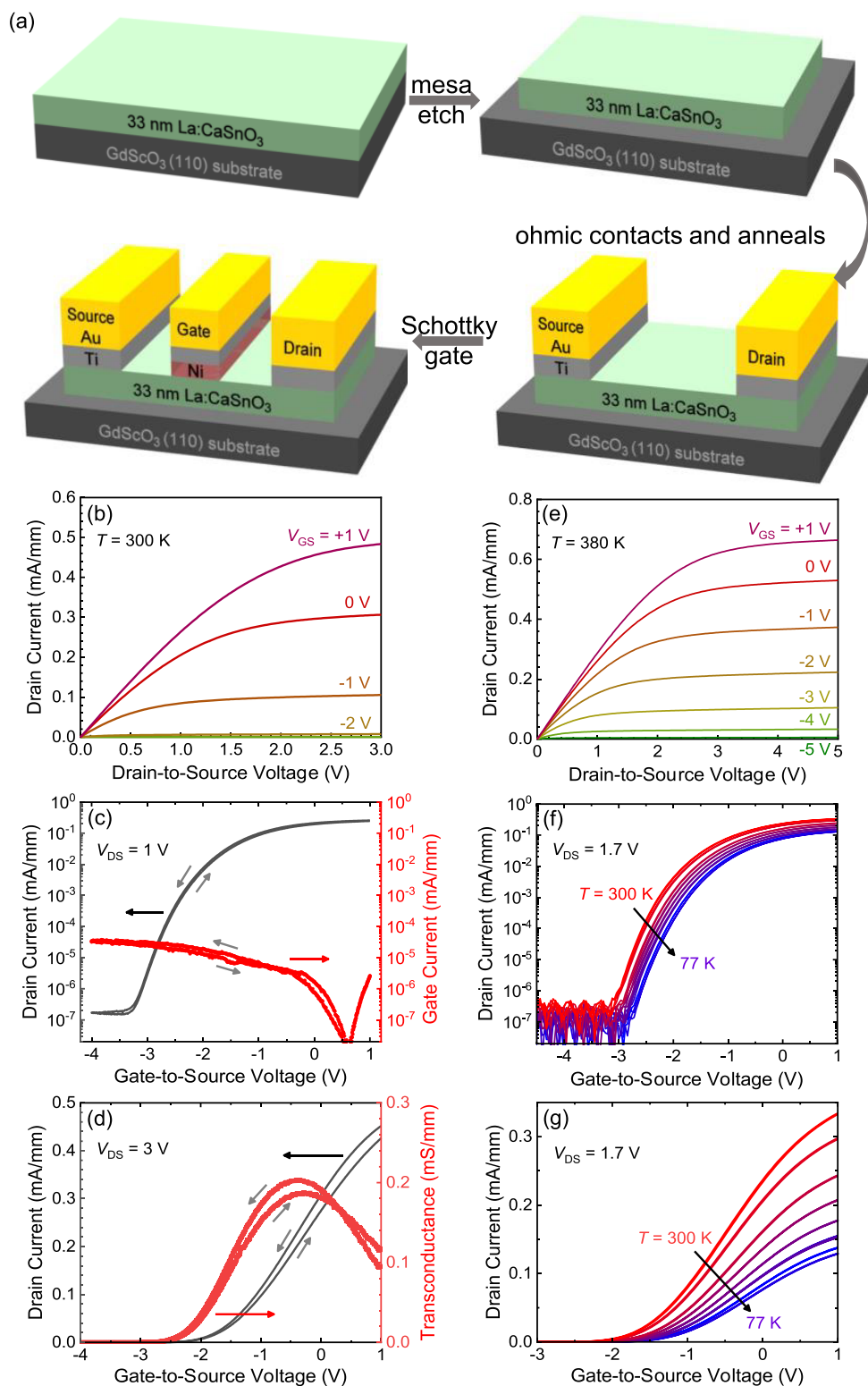


Figure 4. Fabrication and electrical characterization of the La:CaSnO₃ MESFET with $L_{DS} = 9 \mu\text{m}$, $L_G = 3 \mu\text{m}$, and $W_{ch} = 50 \mu\text{m}$. (a) Fabrication steps for the La:CaSnO₃ MESFETs. (b) Room-temperature drain current I_D versus drain-to-source voltage V_{DS} for the La:CaSnO₃ MESFET device for different gate-to-source voltages, V_{GS} . (c) Semilog plot of drain current I_D and gate current I_G versus gate-to-source V_{GS} for the same device at room temperature. (d) Change in drain current and extrinsic transconductance with respect to gate-to-source voltage V_{GS} for the same device at room temperature. (e) Output characteristics at an elevated temperature of 380 K. (f, g) Temperature-dependent transfer characteristics at $V_{DS} = 1.7 \text{ V}$ on a (f) semilog plot and a (g) linear plot.

energy by expanding.³⁴ Table S1 compares this effect to previous observations in SrTiO₃,³⁴ showing that the effect is about 10 times larger than that of SrTiO₃.

Figure 3d shows the room-temperature Hall mobilities ($\mu_{300\text{K}}$) as a function of carrier concentration n_{3D} . This result shows that the mobility increases with decreasing carrier

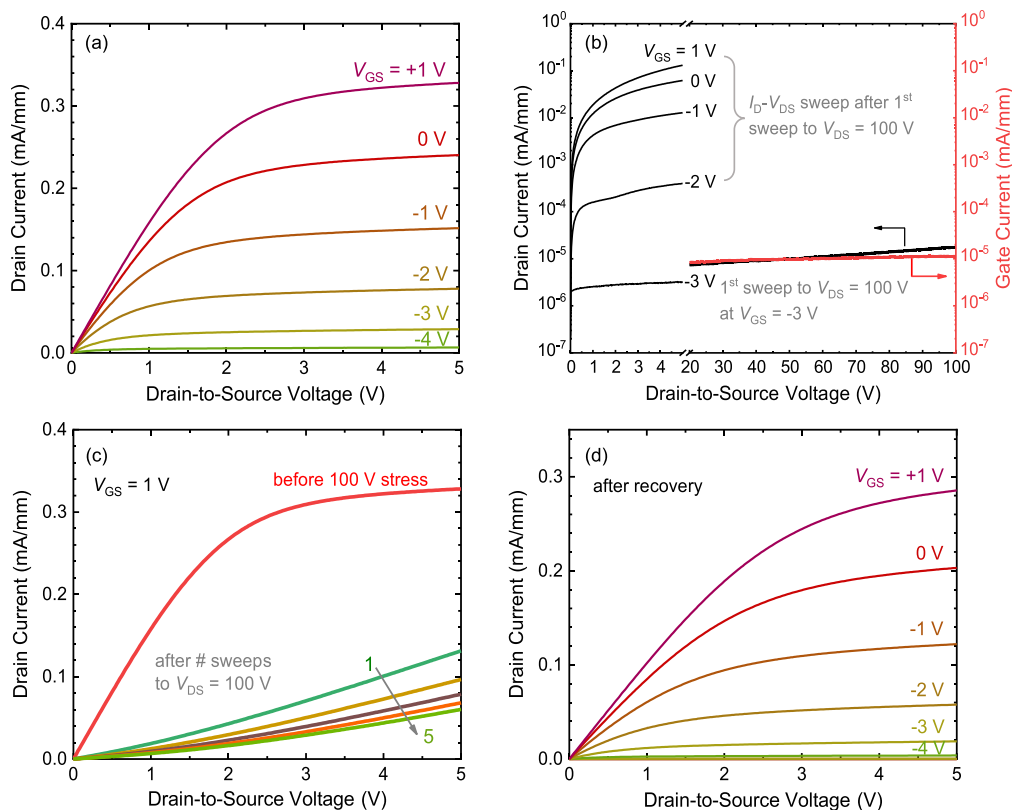


Figure 5. High-voltage performance of a CaSnO_3 MESFET with $L_{\text{DS}} = 15 \mu\text{m}$, $L_{\text{G}} = 3 \mu\text{m}$, and $L_{\text{GD}} = 9 \mu\text{m}$ at 300 K. (a) Output characteristics up to $V_{\text{DS}} = 5 \text{ V}$ for varying gate voltages V_{GS} . (b) Drain current I_{D} versus drain-to-source voltage V_{DS} for different gate-to-source voltages V_{GS} after sweeping the device to $V_{\text{DS}} = 100 \text{ V}$ in the off-state ($V_{\text{GS}} = -3 \text{ V}$). The plot to the right shows the drain current and gate leakage current of the same device up to $V_{\text{DS}} = 100 \text{ V}$ in the off-state. (c) Output characteristics of a $\text{La}:\text{CaSnO}_3$ MESFET up to $V_{\text{DS}} = 5 \text{ V}$ taken before and after stressing the device to $V_{\text{DS}} = 100 \text{ V}$ in the off-state. The plot shows degradation of the drain current with each round of stress measurement. (d) Output characteristics of the device for varying gate voltages, V_{GS} , after a recovery time of ~ 2 days, depicting current recovery to almost the same values as shown in (a).

concentration, a trend which is different from both SrSnO_3 ²⁷ and BaSnO_3 .⁵ Quantitatively, the maximum mobility of $42 \text{ cm}^2 \text{ V}^{-1} \text{ s}^{-1}$ is achieved at the lowest carrier concentration of $3.3 \times 10^{19} \text{ cm}^{-3}$, and the maximum conductivity of $634 \text{ S} \cdot \text{cm}^{-1}$ is achieved at the highest carrier concentration of $1.6 \times 10^{20} \text{ cm}^{-3}$.

One of the most attractive features of CaSnO_3 is its wide band gap. Previous studies have measured the band gap with diffuse reflectance to be $\sim 4.4 \text{ eV}$, and they have determined the band gap to be direct and the transition to be dipole-allowed.^{2,3} Such a large direct band gap would be an exceptional asset to CaSnO_3 , especially given the successful demonstration of doping in this study, as it may give rise to its application in UV optoelectronics. DFT calculations of the band structure of our strained films in Figure S8, predicts a direct gap of 4.19 eV (at Γ). This energy is only slightly less than the gap reported by Weston *et al.*²¹ of 4.3 eV . To experimentally measure the band gap of our films, we performed spectroscopic ellipsometry. Figure S8 shows a reasonably good agreement between experiment and calculation, suggesting a direct band gap of $\sim 4.2 \text{ eV}$ in strained CaSnO_3 films. However, to experimentally determine the band gap, we also fitted the absorption edge, as shown in Figure S9 for both undoped (Figure S9a) and doped (Figure S9b) films. These fittings yielded a direct gap of 4.64 eV , for the undoped sample, $\sim 0.2 \text{ eV}$ greater than the gap previously measured for ceramic powders.^{2,3} The direct gap of the doped film was

found to be slightly larger, 4.68 eV . Future studies should be conducted to better understand this gap, perhaps using angle-resolved photoemission spectroscopy, and to manipulate the nature of this gap, possibly through strain engineering or chemical modification.

Ultimately, the goal of researching a semiconductor is to exploit its properties in an electronic device. To demonstrate the capability of CaSnO_3 for device operation, we fabricated metal–semiconductor field-effect transistors (MESFETs) by using CaSnO_3 as the channel material. The fabrication procedure is shown in Figure 4a, where the starting sample consisted of a 33-nm -thick $\text{La}:\text{CaSnO}_3$ film grown on a GdScO_3 (110) substrate with $n_{\text{3D}} = 3.3 \times 10^{19} \text{ cm}^{-3}$. Figure 4b shows the room-temperature output characteristics of a $\text{La}:\text{CaSnO}_3$ MESFET with source-to-drain spacing, L_{DS} , of $9 \mu\text{m}$, gate length, L_{G} , of $3 \mu\text{m}$, and width, W , of $50 \mu\text{m}$. The drain current, I_{D} , at a gate-to-source voltage, V_{GS} , of $+1 \text{ V}$ is 0.48 mA/mm at a drain-to-source voltage, V_{DS} , of 3 V . The devices show linear turn-on characteristics and good saturation. The transfer characteristics of the same device are shown in Figure 4c. The MESFET operates in depletion mode and has a threshold voltage of -2.5 V . The on–off ratio is $>10^6$ and the off-state current is $<10^{-6} \text{ mA/mm}$, where the off-state current is limited by leakage through the Schottky gate electrode. This behavior is expected in MESFET device geometry, where no gate insulator exists. The minimum subthreshold slope, SS , is 233 mV/dec , measured in the

current range between 10^{-6} and 10^{-5} mA/mm. The linear-mode transfer characteristics are shown in Figure 4d. Only a small hysteresis is observed between forward and reverse sweeps in this gate voltage range, and at $V_{DS} = 3$ V, the peak transconductance g_m was found to be ~ 0.2 mS/mm.

Temperature-dependent measurements were also performed on this device, and the results are shown in Figure 4e. Interestingly, the drive current improved to 0.62 mA/mm (0.68 mA/mm) at $T = 380$ K and $V_{DS} = +3$ (+5 V). Subthreshold measurements at different temperatures are shown in Figure 4f, where, surprisingly, the subthreshold slope did not decrease in proportion to temperature. While $SS = 233$ mV/dec at $T = 300$ K, SS decreased to only 198 mV/dec at $T = 77$ K. Given the Schottky nature of the gate electrode, this could suggest that charge trapping in the bulk of La:CaSnO₃ plays a role in limiting the efficiency of the gate modulation. Another possibility could be the formation of an insulating layer at the Ni/La:CaSnO₃ surface. This possibility is supported by capacitance–voltage measurement (Figure S10), which shows that the capacitance saturates as the gate voltage is made more positive. This saturation is not expected in a MESFET and is more reminiscent of a metal-oxide field-effect transistor (MOSFET). This lower-than-expected gate capacitance is one possible reason for the low drive current in our devices. Finally, the temperature-dependent transfer characteristics are shown in Figure 4g, where I_D was found to decrease by roughly 1/2 going from 300 K to 77 K. Since the film itself displays metallic behavior, as shown in the Hall measurements taken before fabrication in Figure S11, this temperature dependence must arise from the contacts. This, in turn, suggests that the contacts still have a thermionic component and that further improvement could be achieved by using a recessed gate design with higher doping in the contact regions, as previously demonstrated for SrSnO₃ MESFETs.³⁵

Given the potential of CaSnO₃ for high-power devices due to its large band gap, we also performed high-voltage measurements on these devices. For these measurements, we chose a device with $L_{DS} = 15$ μ m and $L_G = 3$ μ m and gate-to-drain spacing, L_{GD} , of 9 μ m. The room-temperature output characteristics of this device are shown in Figure 5a, where the measurements were taken before the application of high voltages. This device was initially measured out to $V_{DS} = 5$ V and displayed good saturation and slightly lower drive current than the device in Figure 4 owing to its longer L_{DS} . The high-voltage measurements are shown in Figure 5b. Here, the device was biased into the off-state ($V_{GS} = -3$ V), and then V_{DS} swept from 0 to 100 V, followed by a repeat of the I_D – V_{DS} measurements, which are also shown in the plot. The graph shows that the device did not suffer catastrophic breakdown and remained operational after the high-voltage pulse, though with decreased drive current. This procedure of applying $V_{DS} = 100$ V and then remeasuring the device at low voltage was repeated five times. The low-voltage on-state results (at $V_{GS} = +1$ V) after each set of repeated measurements are shown in Figure 5c. The drain current is seen to continue to decrease, though no catastrophic failure is observed, and the device structure remains intact. After performing these measurements, the device was stored in a vacuum for 2 days and then heated to $T = 380$ K and remeasured. These results are shown in Figure 5d, where it was observed that the device nearly completely recovered and showed a performance similar to the original measurements.

The current collapse observed at high voltages is similar to that observed in GaN high electron mobility transistors^{36,37} and has been related to hot carriers filling traps either at the surface or in the bulk layers, which then deplete the channel, leading to reduced current. Therefore, in the future, techniques to minimize hot-carrier trapping, including the use of a field-plate geometry and surface passivation,³⁸ will be important to assess the ultimate high-voltage capabilities of CaSnO₃. Additionally, the role of ionic conduction in stannates³⁹ under high applied bias may also become an important factor and should be investigated.

DISCUSSION

A comparison of CaSnO₃'s doping behavior to those of the other alkaline earth stannates is illuminating. A plot of μ_{300K} versus n_{3D} is shown in Figure S12. The peak mobility in CaSnO₃ (42 cm² V⁻¹ s⁻¹) is below that of SrSnO₃ (72.5 cm² V⁻¹ s⁻¹)⁷ and BaSnO₃ (120 cm² V⁻¹ s⁻¹)⁵ grown with the same technique. This is explained by the smaller band dispersion of CaSnO₃ resulting in a heavier conduction band effective mass (m^*).² We note that, in these highly polar materials, an increase in m^* can cause polaronic effects that amplify its effect on mobility beyond the proportionality implied by the Drude formula.⁴⁰ Finally, we point out the qualitative differences in μ_{300K} versus n_{3D} apparent in Figure S12. Thin-film BaSnO₃ has a mostly positive correlation between dopant concentration and mobility due to the carriers screening charged dislocation scattering,^{5,6} and SrSnO₃'s mobility is nearly independent of carrier concentration due to phonon scattering dominating the room-temperature mobility.²⁷ However, CaSnO₃ has a mobility that is *negatively* correlated with the carrier concentration. This behavior is typically seen in extremely pure high-quality crystals such as Si⁴¹ and suggests a low defect concentration where electrons are predominantly scattered by the ionized La donors themselves.

The fact that we achieved successful n-type doping of CaSnO₃ without facing any major obstacles raises the question, Why did previous attempts fail? The most noteworthy attempt was by Wei *et al.*, who deposited La_{0.03}Ca_{0.97}SnO₃ with PLD and failed to achieve measurable conductivity.²⁰ There are four major differences between this study and our own: (1) Wei *et al.* used highly lattice-mismatched (-3.2%) and tilt-mismatched ($>6^\circ$) LaAlO₃ substrates, whereas this study used closely lattice-matched GdScO₃ substrates. (2) Wei *et al.* used PLD, whereas this study used hybrid MBE. (3) Wei *et al.* used a substrate temperature of 750 $^\circ$ C, whereas we used a much higher substrate temperature of 950 $^\circ$ C. (4) Wei *et al.* used a doping fraction fixed at 3% in their target, whereas we used an effusion cell at various temperatures to introduce La. Both high lattice mismatch and high-energy ions from PLD are known to introduce defects that could conceivably compensate carriers and lead to insulating films in their study.

It is also interesting to discuss how the doping limitations of CaSnO₃ affect the device performance and what avenues for improvement are possible. While the La:CaSnO₃ MESFETs in this study demonstrate the basic capabilities of field-effect transistors based on CaSnO₃, a considerable increase in the performance is needed. The low drive current is a result of (1) the relatively low channel doping, which limits the intrinsic current carrying capacity of the devices, and (2) the high contact resistance (~ 500 Ω -mm), which is also a result of the low doping. Much higher doping is needed to create tunneling

contacts, and the use of a thinner channel region and a recessed-gate geometry³⁵ could allow devices to achieve higher drive current and transconductance. An estimate of the field-effect mobility in our devices was obtained from the intrinsic g_m (0.22 mS/mm) and the device capacitance which yielded an apparent field-effect mobility, μ_{FE} , of 1.2 cm²/(V s). However, this value does not reflect the true transport mobility of CaSnO₃, due to the high contact resistance and nonideal device geometry ($L_G \ll L_{DS}$) for mobility extraction. Future experiments using more suitable device geometries are needed in order to determine an accurate value of μ_{FE} . While this work shows that controllable doping is possible, the performance did vary between different devices on this wafer. Figure S13 shows the I_D – V_{GS} characteristics of several devices fabricated on the same wafer, and Table S2 lists the device parameters and performance metrics. We attribute these differences primarily to variations in the contacts and not the intrinsic material properties, since at these doping levels even small variations in the dopant concentration and interfacial properties can lead to large variations in contact resistance.

OUTLOOK

We suggest four directions for future work. First, studies should be carried out to precisely understand what mechanisms limit the doping concentrations and mobilities of these doped films. This might include identifying compensation mechanisms that prevent dilute doping, understanding whether self-compensation or secondary phase precipitation processes prevent heavier doping, and precisely resolving electron scattering mechanisms. If these limiting factors can be understood and rectified, then higher mobilities and a wider range of doping concentrations can be achieved. Second, given the direct band gap of strained CaSnO₃ films, CaSnO₃ may find applications in UV optoelectronics. Since most advanced optoelectronic devices are bipolar, the exploration of p-type doping strategies, as already done for BaSnO₃,^{42,43} might be a next step. Third, successful doping in CaSnO₃ raises the question of whether other materials previously thought to be undopable can be doped. Specifically, MgSnO₃ and ZnSnO₃ are metastable perovskites that have been epitaxially stabilized,⁴⁴ but never doped. Finally, CaSnO₃ should be explored as a component in heterostructures, for instance, by serving as a wide-band-gap modulation donor to perovskites with similar lattice parameters.

CONCLUSIONS

This study demonstrates the adsorption-controlled growth of CaSnO₃—a material previously deemed undopable—with controllable doping using hybrid MBE. Chemical doping resulted in 100% dopant activation with free electron concentrations ranging from 3.3×10^{19} to 1.6×10^{20} cm^{−3}. A maximum room-temperature mobility of 42 cm² V^{−1} s^{−1} at $n_{3D} = 3.3 \times 10^{19}$ cm^{−3} was achieved. Despite comparable ionic radii of La, increasing the doping concentration resulted in an expansion of the out-of-plane lattice parameters, which is attributed to an electronic effect based on the DFT calculations. The surprising robustness and predictability of the doping also allowed us to fabricate and demonstrate the operation of CaSnO₃-based field-effect transistors. These results encourage revisiting CaSnO₃ as a viable ultrawide-band-gap semiconductor for devices.

EXPERIMENTAL SECTION

Film Growth. The La:CaSnO₃ thin films were grown by using hybrid molecular beam epitaxy (hMBE). This approach employs conventional effusion cells for lanthanum and calcium, hexamethylditin (HMDT) as a metal–organic precursor for tin, and an inductively coupled RF plasma for oxygen. The reader is referred to Prakash *et al.* for more details about the technique as applied to BaSnO₃.²⁴ Figure S14 summarizes the technique as applied to La:CaSnO₃. All films were grown on GdScO₃ (110) single-crystal substrates, indexed in the *Pbnm* setting (CrysTec GmbH). All films were grown at a fixed substrate temperature of 950 °C as measured with a floating thermocouple. The substrates were cleaned *in situ* with oxygen plasma for 25 min prior to film deposition. Ca was sublimed from a titanium crucible with its BEP fixed at 2.65×10^{-8} mbar, as measured by a retractable beam flux monitor before growth. The oxygen flow was set to 0.7 standard cubic centimeters per minute (sccm) to achieve an oxygen background pressure of 5×10^{-6} Torr while applying 250 W of RF power to the plasma coil. These conditions achieved a growth rate of 22 nm per hour.

HMDT vapor entered the chamber through a heated gas injector (E-Science, Inc.) in an effusion cell port that was in direct line-of-sight with the substrate. The HMDT vapor reached the injector *via* a linear leak valve followed by a capacitance manometer (Baratron, MKS Instruments, Inc.), the valve opening serving as the control variable and the manometer pressure serving as the process variable in a control loop. The HMDT bubbler was held at ~75 °C to provide sufficient HMDT vapor pressure, and the HMDT vapor lines were held at a slightly higher temperature of ~85 °C to prevent HMDT condensation in the lines. Temperatures were controlled with resistive heating tape powered by autotransformers, and the temperatures were monitored with grounded thermocouples tack-welded to the crucible or lines. The injector itself was held at 60 °C.

Cation stoichiometry (Sn:Ca ratio) was explored by varying the HMDT manometer set point pressure from 200 to 240 mTorr, which achieved a BEP of 2.33×10^{-5} to 3.07×10^{-5} mbar. A gas sensitivity factor of 1.0 (relative to nitrogen calibration) was used, equal to that used for Ca. Each film during stoichiometry optimization was grown for 180 min. La was used as a dopant motivated by the similar ionic radii of La³⁺ and Ca²⁺ (Figure S7). To introduce La, a tantalum-crucible high-temperature effusion cell was used (Dr. Eberl-MBE Komponenten GmbH). During cation stoichiometry optimization, the La cell temperature was fixed at 1190 °C to provide carriers whose mobilities could be used to infer stoichiometry. The carrier density was then varied by changing the La cell temperature from 1120 to 1205 °C. Each film was grown for 90 min.

Film Characterization. A Rigaku SmartLab XE instrument was used for X-ray scattering measurements. Film thicknesses were extracted from the X-ray reflectivity (XRR). Reciprocal space maps (RSMs) were collected by scanning ω while using the HyPix-3000 detector in one-dimensional mode to simultaneously resolve 2θ . Electric transport measurements were performed in a Quantum Design physical property measurement system (DynaCool) using aluminum wire that bonds directly to the film in the van der Pauw geometry.

STEM specimens were prepared using a Thermo Fisher Scientific Helios G4 UX focused ion beam (FIB) with standard lift-out and thinning methods for imaging the [001]_{orth} zone axis. STEM imaging and EELS mapping were performed on a Thermo Fisher Scientific Spectra 300 X-CFEG operating at 300 kV with a convergence angle of 30 mrad. The inner and outer collection angles for HAADF-STEM imaging were approximately 60 and 200 mrad, respectively. All images were acquired as series of fast acquisitions and subsequently aligned and summed to produce high signal-to-noise ratio images while minimizing scan artifacts. EEL spectra were acquired with a Gatan Continuum system equipped with a scintillator CMOS camera. Each spectrum was background-subtracted, and the relevant elemental edges were summed to produce elemental maps.

Ellipsometry measurements were done on a J. A. Woollam M-2000 at Drexel University. The light source was composed of a deuterium

lamp and a QTH lamp, allowing measurements over wavelengths from 210 to 1650 nm. A bare GdScO₃ substrate as well as the samples were measured at five different incident angles (65, 67.5, 70, 72.5, and 75 degrees). The results were modeled using CompleteEASE software, first for the substrate and then for the film + substrate data, obtaining refractive index n and extinction coefficient k values, using film thickness as an input.

Device Fabrication. The MESFET fabrication procedure started by using optical lithography to define the active device area, and Ar⁺ ion milling was performed for 15 min to create the mesa regions. The mesa was intentionally overetched to ensure the La:CaSnO₃ was completely removed in the field regions. After mesa isolation, a second optical lithography cycle was performed and source/drain (S/D) contacts were defined, followed by evaporation of 100 nm Au/75 nm Ti using electron-beam evaporation. After solvent lift-off, two-terminal I – V curves were taken for the S/D contacts to determine the quality of the contacts. The contacts were initially observed to have high resistance and were therefore annealed at a series of increasing temperatures until good ohmic behavior was observed, similar to previous studies on SrSnO₃.⁴⁵ These anneals were performed in an N₂ environment at sequential temperatures of 200, 300, and 320 °C for 6.5 min each. After each anneal, two-terminal I – V curves of the S/D contacts were taken to monitor the improvement in current injection into the contacts. The on-resistance improved from ~951 k Ω –mm in the as-deposited contacts to 1.22 k Ω –mm at 300 °C, while no further improvement was seen after the 320 °C anneal. The results of these measurements are described in the [Supporting Information Figure S15](#). After the S/D contact annealing experiments were completed, optical lithography was used again to pattern the Schottky gate electrodes, followed by 80 nm Au/10 nm Ti/90 nm Ni evaporation and solvent lift-off. After fabrication, the devices were measured using a Keysight B1500 semiconductor parameter analyzer under a vacuum at $\sim 2 \times 10^{-6}$ Torr.

Density Functional Theory Calculations. The calculations are based on density functional theory^{46,47} and the HSE06 hybrid functional^{48,49} as implemented in the VASP code.⁵⁰ The interactions between valence electrons and ionic cores were treated using the projector-augmented potential (PAW) method,⁵¹ with the following valence configurations: Ca: 3p⁶4s², Sn: 5s²5p², O: 2s²2p², La: 5s²5p⁶6s² 5d¹. We used the standard mixing parameter of 25% in the HSE06 and a plane wave cutoff of 500 eV. Within the generalized gradient approximation revised for solids, PBEsol, we performed calculations adding one electron to supercells of 40 and 320 atoms, representing concentrations of 2.0×10^{21} cm⁻³ and 2.5×10^{20} cm⁻³, using only the Γ point for integrations over the Brillouin zone. The simulations of the epitaxially strained doped and undoped CaSnO₃ were carried out by having the [110]_{orth} and [001]_{orth} and as a and b in-plane lattice vectors constrained to the substrate lattice parameters and allowing the out-of-plane c lattice parameter along the [110]_{orth} direction to relax. The in-plane lattice parameters a and b were expanded by +0.48% and +0.67% with respect to their theoretical equilibrium lattice parameter to represent the tensile stress from the deposition on the GdScO₃ substrate, also with [110]_{orth} as the out-of-plane direction.

To investigate the pure electronic effect, we performed calculations by adding only one extra electron to the supercell of perfect bulk CaSnO₃ and allowing the c -axis ([110]_{orth}) to relax; for the pure size effect, we replaced one Ca with one La, removed the extra electron that would populate the conduction band minimum, and allowed the c -axis to relax; and for the combined electronic and size effects, we performed calculations by replacing one Ca with La, including the extra electron in the conduction band, and allowing the c -axis to relax.

Structural characterization, optical measurements, temperature-dependent transport measurements, additional device results, and band structure calculations ([PDF](#))

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Author Contributions

F.L. and P.G. are both equally contributing authors. F.L., P.G., T.K.T., S.J.K., and B.J. conceived the idea and designed experiments. Films were grown and characterized with XRD

ASSOCIATED CONTENT

SI Supporting Information

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and AFM by F.L. and T.K.T. Electrical transport measurements were performed by F.L. and A.K.M. Transistor fabrication was performed by P.G., while electrical testing was done by P.G. and J.W. under the supervision of S.J.K. STEM measurements were done by M.A.S. under the guidance of L.F.K. I.E. performed DFT calculations under the direction of A.J. Ellipsometry measurements were done by D.B., and diffraction simulations were carried out by S.J.M. F.L., P.G., and T.K.T. wrote the manuscript with input from all authors. B.J. and S.J.K. directed and organized the materials and device aspects of the project, respectively.

Notes

The authors declare no competing financial interest.

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REFERENCES

- (1) Kim, H. J.; Kim, U.; Kim, H. M.; Kim, T. H.; Mun, H. S.; Jeon, B.-G.; Hong, K. T.; Lee, W.-J.; Ju, C.; Kim, K. H.; Char, K. High Mobility in a Stable Transparent Perovskite Oxide. *Applied Physics Express* **2012**, *5* (6), No. 061102.
- (2) Mizoguchi, H.; Eng, H. W.; Woodward, P. M. Probing the Electronic Structures of Ternary Perovskite and Pyrochlore Oxides Containing Sn^{4+} Or Sb^{5+} . *Inorg. Chem.* **2004**, *43* (5), 1667–1680.
- (3) Zhang, W.; Tang, J.; Ye, J. Structural, Photocatalytic, and Photophysical Properties of Perovskite MSnO_3 ($\text{M} = \text{Ca}, \text{Sr}, \text{And Ba}$) Photocatalysts. *J. Mater. Res.* **2007**, *22* (7), 1859–1871.
- (4) Paik, H.; Chen, Z.; Lochocki, E.; Seidner, H. A.; Verma, A.; Tanen, N.; Park, J.; Uchida, M.; Shang, S.; Zhou, B.-C.; Brützmam, M.; Uecker, R.; Liu, Z.-K.; Jena, D.; Shen, K. M.; Muller, D. A.; Schlom, D. G. Adsorption-Controlled Growth of La-Doped BaSnO_3 by Molecular-Beam Epitaxy. *APL Materials* **2017**, *5* (11), No. 116107.
- (5) Prakash, A.; Xu, P.; Faghaninia, A.; Shukla, S.; Ager, J. W.; Lo, C. S.; Jalan, B. Wide Bandgap BaSnO_3 Films with Room Temperature Conductivity Exceeding 10^4 S cm^{-1} . *Nat. Commun.* **2017**, *8* (1), 15167.
- (6) Mun, H.; Kim, U.; Min Kim, H.; Park, C.; Hoon Kim, T.; Joon Kim, H.; Hoon Kim, K.; Char, K. Large Effects of Dislocations on High Mobility of Epitaxial Perovskite $\text{Ba}_{0.96}\text{La}_{0.04}\text{SnO}_3$ Films. *Appl. Phys. Lett.* **2013**, *102* (25), No. 252105.
- (7) Truttmann, T. K.; Liu, F.; Garcia-Barriocanal, J.; James, R. D.; Jalan, B. Strain Relaxation via Phase Transformation in High-Mobility SrSnO_3 Films. *ACS Applied Electronic Materials* **2021**, *3* (3), 1127–1132.
- (8) Chaganti, V. R. S. K.; Prakash, A.; Yue, J.; Jalan, B.; Koester, S. J. Demonstration of a Depletion-Mode SrSnO_3 n-Channel MESFET. *IEEE Elec. Dev. Lett.* **2018**, *39* (9), 1381.
- (9) Wen, J.; Chaganti, V. R. S. K.; Truttmann, T. K.; Liu, F.; Jalan, B.; Koester, S. J. SrSnO_3 Metal-Semiconductor Field-Effect Transistor with GHz Operation. *IEEE Elect. Dev. Lett.* **2021**, *42* (1), 74–77.
- (10) Wang, T.; Thoutam, L. R.; Prakash, A.; Nunn, W.; Haugstad, G.; Jalan, B. Defect-Driven Localization Crossovers in MBE-Grown La-Doped SrSnO_3 Films. *Physical Review Materials* **2017**, *1* (6), No. 061601.
- (11) Wang, T.; Prakash, A.; Dong, Y.; Truttmann, T.; Bucsek, A.; James, R.; Fong, D. D.; Kim, J.-W.; Ryan, P. J.; Zhou, H.; Birol, T.; Jalan, B. Engineering SrSnO_3 Phases and Electron Mobility at Room Temperature Using Epitaxial Strain. *ACS Appl. Mater. Interfaces* **2018**, *10* (50), 43802–43808.
- (12) Truttmann, T.; Prakash, A.; Yue, J.; Mates, T. E.; Jalan, B. Dopant Solubility and Charge Compensation in La-Doped SrSnO_3 Films. *Appl. Phys. Lett.* **2019**, *115* (15), No. 152103.
- (13) Glerup, M.; Knight, K. S.; Poulsen, F. W. High Temperature Structural Phase Transitions in SrSnO_3 Perovskite. *Mater. Res. Bull.* **2005**, *40* (3), 507–520.
- (14) Mountstevens, E. H.; Attfield, J. P.; Redfern, S. A. T. Cation-Size Control of Structural Phase Transitions in Tin Perovskites. *J. Phys.: Condens. Matter* **2003**, *15* (49), 8315–8326.
- (15) Redfern, S. A. T.; Chen, C. J.; Kung, J.; Chaix-Pluchery, O.; Kreisel, J.; Salje, E. K. H. Raman Spectroscopy of CaSnO_3 at High Temperature: a Highly Quasi-Harmonic Perovskite. *J. Phys.: Condens. Matter* **2011**, *23* (42), No. 425401.
- (16) Schneider, B. W.; Liu, W.; Li, B. Searching for Post-Perovskite Transition in CaSnO_3 at High Pressure: an Ultrasonic Velocity Study to 18 GPa. *High Pressure Research* **2008**, *28* (3), 397–404.
- (17) Tateno, S.; Hirose, K.; Sata, N.; Ohishi, Y. Structural Distortion of CaSnO_3 Perovskite Under Pressure and the Quenchable Post-Perovskite Phase as a Low-Pressure Analogue to MgSiO_3 . *Physics of the Earth and Planetary Interiors* **2010**, *181* (1), 54–59.
- (18) Liferovich, R. P.; Mitchell, R. H. A Structural Study of Ternary Lanthanide Orthosulfate Perovskites. *J. Solid State Chem.* **2004**, *177* (6), 2188–2197.
- (19) Baliga, B. J. Semiconductors For High-Voltage, Vertical Channel Field-Effect Transistors. *J. Appl. Phys.* **1982**, *53* (3), 1759–1764.
- (20) Wei, M.; Cho, H. J.; Ohta, H. Tuning of the Optoelectronic Properties for Transparent Oxide Semiconductor ASnO_3 by Modulating the Size of A-Ions. *ACS Applied Electronic Materials* **2020**, *2* (12), 3971–3976.
- (21) Weston, L.; Bjaalie, L.; Krishnaswamy, K.; Van de Walle, C. G. Origins of n-Type Doping Difficulties in Perovskite Stannates. *Phys. Rev. B* **2018**, *97* (5), No. 054112.
- (22) Shaili, H.; Salmani, E.; Beraich, M.; Zidane, M.; Taibi, M. h.; Rouchdi, M.; Ez-Zahraouy, H.; Hassanain, N.; Mzerd, A. Higher Conductivity and Enhanced Optoelectronic Properties of Chemically

Grown Nd-Doped CaSnO_3 Perovskite Oxide Thin Films. *ACS Omega* **2021**, 6 (48), 32537–32547.

(23) Liu, Q.; Jin, F.; Li, B.; Geng, L. Structure and Band Gap Energy of CaSnO_3 Epitaxial Films on LaAlO_3 Substrate. *J. Alloys Compd.* **2017**, 717, 55–61.

(24) Prakash, A.; Xu, P.; Wu, X.; Haugstad, G.; Wang, X.; Jalan, B. Adsorption-Controlled Growth and the Influence of Stoichiometry on Electronic Transport in Hybrid Molecular Beam Epitaxy-Grown BaSnO_3 Films. *Journal of Materials Chemistry C* **2017**, 5 (23), 5730–5736.

(25) Dirsyte, R.; Schwarzkopf, J.; Wagner, G.; Fornari, R.; Lienemann, J.; Busch, M.; Winter, H. Thermal-Induced Change in Surface Termination Of $\text{DyScO}_3(110)$. *Surf. Sci.* **2010**, 604 (21), L55–L58.

(26) Kleibeuker, J. E.; Koster, G.; Siemons, W.; Dubbink, D.; Kuiper, B.; Blok, J. L.; Yang, C.-H.; Ravichandran, J.; Ramesh, R.; ten Elshof, J. E.; Blank, D. H. A.; Rijnders, G. Atomically Defined Rare-Earth Scandate Crystal Surfaces. *Adv. Funct. Mater.* **2010**, 20 (20), 3490–3496.

(27) Truttman, T. K.; Zhou, J.-J.; Lu, I. T.; Rajapitamahuni, A. K.; Liu, F.; Mates, T. E.; Bernardi, M.; Jalan, B. Combined Experimental-Theoretical Study of Electron Mobility-Limiting Mechanisms in SrSnO_3 . *Communications Physics* **2021**, 4 (1), 241.

(28) Mott, N. F. The Minimum Metallic Conductivity. *Int. Rev. Phys. Chem.* **1985**, 4 (1), 1–18.

(29) Allen, S. J.; Raghavan, S.; Schumann, T.; Law, K.-M.; Stemmer, S. Conduction Band Edge Effective Mass of La-Doped BaSnO_3 . *Appl. Phys. Lett.* **2016**, 108 (25), No. 252107.

(30) Nunn, W.; Prakash, A.; Bhowmik, A.; Haislmaier, R.; Yue, J.; Garcia Lastra, J. M.; Jalan, B. Frequency- and Temperature-Dependent Dielectric Response in Hybrid Molecular Beam Epitaxy-Grown BaSnO_3 Films. *APL Mater.* **2018**, 6 (6), No. 066107.

(31) Trari, M.; Doumerc, J.-P.; Dordor, P.; Pouchard, M.; Behr, G.; Krabbes, G. Preparation and Characterization of Lanthanum Doped BaSnO_3 . *J. Phys. Chem. Solids* **1994**, 55 (11), 1239–1243.

(32) Glavic, A.; Björck, M. GenX 3: The Latest Generation of an Established Tool. *J. Appl. Crystallogr.* **2022**, 55 (4), 1063–1071.

(33) Van de Walle, C. G.; Martin, R. M. “Absolute” Deformation Potentials: Formulation and Ab Initio Calculations For Semiconductors. *Phys. Rev. Lett.* **1989**, 62 (17), 2028–2031.

(34) Janotti, A.; Jalan, B.; Stemmer, S.; Van de Walle, C. G. Effects of Doping on the Lattice Parameter of SrTiO_3 . *Appl. Phys. Lett.* **2012**, 100 (26), No. 262104.

(35) Chaganti, V. R. S. K.; Truttman, T. K.; Liu, F.; Jalan, B.; Koester, S. J. SrSnO_3 Field-Effect Transistors with Recessed Gate Electrodes. *IEEE Electron Device Lett.* **2020**, 41 (9), 1428–1431.

(36) Vetury, R.; Zhang, N. Q.; Keller, S.; Mishra, U. K. The Impact of Surface States on the DC And RF Characteristics of AlGaIn/GaN HFETs. *IEEE Trans. Electron Devices* **2001**, 48 (3), 560–566.

(37) Mizutani, T.; Ohno, Y.; Akita, M.; Kishimoto, S.; Maezawa, K. A Study on Current Collapse In AlGaIn/GaN HEMTs Induced by Bias Stress. *IEEE Trans. Electron Devices* **2003**, 50 (10), 2015–2020.

(38) Jiang, H.; Liu, C.; Chen, Y.; Lu, X.; Tang, C. W.; Lau, K. M. Investigation of In Situ SiN as Gate Dielectric And Surface Passivation for GaN MISHEMTs . *IEEE Trans. Electron Devices* **2017**, 64 (3), 832–839.

(39) Belthle, K. S.; Gries, U. N.; Mueller, M. P.; Kemp, D.; Prakash, A.; Rose, M. A.; Börgers, J. M.; Jalan, B.; Gunkel, F.; Souza, R. A. D. Quantitative Determination of Native Point-Defect Concentrations at the ppm Level in Un-Doped BaSnO_3 Thin Films. *Adv. Funct. Mater.* **2022**, 32 (19), No. 2113023.

(40) Zhou, J.-J.; Bernardi, M. Predicting Charge Transport in the Presence of Polarons: the Beyond-Quasiparticle Regime in SrTiO_3 . *Physical Review Research* **2019**, 1 (3), No. 033138.

(41) Mousty, F.; Ostojia, P.; Passari, L. Relationship between Resistivity and Phosphorus Concentration in Silicon. *J. Appl. Phys.* **1974**, 45 (10), 4576–4580.

(42) Kim, H. M.; Kim, U.; Park, C.; Kwon, H.; Char, K. Thermally Stable pn-Junctions Based on a Single Transparent Perovskite Semiconductor BaSnO_3 . *APL Materials* **2016**, 4 (5), No. 056105.

(43) Wang, J.; Luo, B. Electronic Properties of p-Type BaSnO_3 Thin Films. *Ceram. Int.* **2020**, 46 (16), 25678–25682.

(44) Fujiwara, K.; Minato, H.; Shiogai, J.; Kumamoto, A.; Shibata, N.; Tsukazaki, A. Thin-Film Stabilization Of LiNbO_3 -Type ZnSnO_3 And MgSnO_3 by Molecular-Beam Epitaxy. *APL Materials* **2019**, 7 (2), No. 022505.

(45) Chaganti, V. R. S. K.; Golani, P.; Truttman, T. K.; Liu, F.; Jalan, B.; Koester, S. J. Optimizing Ohmic Contacts to Nd-Doped n-Type SrSnO_3 . *Appl. Phys. Lett.* **2021**, 118 (14), No. 142104.

(46) Kohn, W.; Sham, L. J. Self-Consistent Equations Including Exchange and Correlation Effects. *Phys. Rev.* **1965**, 140 (4A), A1133–A1138.

(47) Hohenberg, P.; Kohn, W. Inhomogeneous Electron Gas. *Phys. Rev.* **1964**, 136 (3B), B864–B871.

(48) Heyd, J.; Scuseria, G. E.; Ernzerhof, M. Hybrid Functionals Based on a Screened Coulomb Potential. *J. Chem. Phys.* **2003**, 118 (18), 8207–8215.

(49) Paier, J.; Marsman, M.; Hummer, K.; Kresse, G.; Gerber, I. C.; Ángyán, J. G. Erratum: “Screened Hybrid Density Functionals Applied to Solids. *J. Chem. Phys.* **2006**, 125 (24), No. 249901.

(50) Kresse, G.; Furthmüller, J. Efficient Iterative Schemes for Ab Initio Total-Energy Calculations Using a Plane-Wave Basis Set. *Phys. Rev. B* **1996**, 54 (16), 11169–11186.

(51) Kresse, G.; Joubert, D. From Ultrasoft Pseudopotentials to the Projector Augmented-Wave Method. *Phys. Rev. B* **1999**, 59 (3), 1758–1775.